## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Syouji NOGAMI et al. Confirmation No. 8539

Serial No.: 10/562,235 Group Art Unit: 2813

Filed : October 31, 2006 Examiner: Sonya D. Mccall Shepard

For: MANUFACTURING METHOD OF SEMICONDUCTOR WAFER AND SEMICONDUCTOR WAFER MANUFACTURED BY THIS METHOD

United States Patent and Trademark Office Customer Service Window, Mail Stop <u>Amendment</u> Randolph Building 401 Dulany Street Alexandria, VA 22314

## REQUEST FOR EXTENSION OF TIME

Sir:

Please extend the time for response to the Official Action dated July 17, 2009 by one month from October 17, 2009 to November 17, 2009. The amount of \$130.00 is submitted concurrently herewith as payment for the fee.

The U.S. Patent and Trademark Office is hereby authorized to credit any overpayment or charge any additional fee to Deposit Account No.19-0089.

Respectfully submitted, Svouii NOGAMI et al.

Sarry I. Hollander Reg. No. 28,566

William S. Boshnick Reg. No. 44,550

November 17, 2009 GREENBLUM & BERNSTEIN, P.L.C. 1950 Roland Clarke Place Reston, VA 20191 (703) 716-1191